

## **TECHNICAL SPEC FOR Wet processing system**

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**System Model:**

**Akrion REARMOUNT**

**Wafer size: 6 inch**

**Application: oxide etch, HF-dip**

**Process flow: HF, IPA, DIW**

**Front- or rear-mount: rear**

**Process Robot End-Effector:**

**Controller: control zone main components pneumatic solenoid panel, heated tank control unit, digital I/O boards (OPTO22)**

**Transfer robot: robot transfer arm, free standing unit**

**Common I/O Station: separate**

**Wafer transfer system:NA**

**Dual buffer queues:**

**PFA Cassettes: Yes**

**Configuration of each wet process modules:**

Tank 1: HF + mixed DI

Tank 3: HF

Vapor dryer: IPA

**Pumps:**

**SECS: installed**

**Vintage:**

**Missing parts:**

**Defected parts:**

**Software: DOS**

**Operating system: 386 computer /Akrion**

### **Photos to Collect**

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- All 4 sides
- Process modules
- Control panel
- Robots
- Loaders
- Chemical cannisters (close-up on chemicals)
- Gauges/Valves
- Exhaust pipes
- Pumps
- Inside all cabinets
- Serial plate
- Spare parts, manuals (if any)